

Indian Nanoelectronics Users Program

Centre for Nano Science and Engineering (CeNSE), IISc. Bangalore



Modeling, Design and Fabrication of Semiconductor Devices and Solar Cell

Syed Sadique Anwer Askari, Dr. Mukul K. Das (Supervisor), Indian School of Mines Dhanbad, Jharkhand Year of PhD Registration: 2014

Experience of Teaching & Research (Supervisor): More than 14 years

Research Group Details:

HDG is working on:

- Group-IV Alloy based Solar Cell,
- Tin incorporated Group-IV Alloy based Transistor-LASER & Photodetector,
- Group III-V compound based Photodetector & High Electron Mobility Transistor (HEMT).

Si/SiGe Heterojunction Solar Cell Bound-to-Continuum Transition in GaAs/AlGaAs QWIP using APSYS

Heterostructured Device Group (HDG)

Research Scholars: Mrs. Bindu Priyadarshini, Mr. Prakash Pareek, Mr. Ravi Ranjan,

Mr. Md. Aref Billaha, Mrs. Lipika Mondal,

Syed Sadique Anwer Askari

Supervisor: Dr. Mukul K. Das, Assoc. Prof., Dept. of Electronics Engg. & Head, Centre of Excellence in Renewable Energy At ISM Under FAST, MHRD

Research Facility at ISM Dhanbad



X-RAY DIFFRACTOMETER (XRD) Used for structural determination and phase identification of the materials.



FTIR SPECTROMETER





FE-SEM SUPRA 55 WITH AIR LOCK, EDS, EBSD
Attachments available with the FE-SEM are
Energy Dispersive Microanalysis (Oxford
Liquid Nitrogen free SDD X MAX 50
EDS), Electron Backscatter Diffraction



FLUORESCENCE SPECTROPHOTOMETER Used to study the photoluminescence phenomenon and to get the idea about the radiative/nonradiative transitions of dopant / host matrix. Used for determination of functional groups of the materials in bulk or thin film form.



THERMOLUMINESCENCE ANALYZERUsed to study the thermoluminescencephenomena, to characterize different defects andto identify different trap levels produced afterenergetic particle radiation/ionizing radiation.



SCANNING ELECTRON MICROSCOPE (SEM) Used to find out Surface morphology and

important

confined stark effect.

Results

Good agreement with the theoretical result [N. Yahyaoui, et.al., "Band

engineering and absorption spectra in compressively strained

Ge_{0.92}Sn_{0.08}/Ge (001) double quantum well for infrared photodetection"

Phys. Status Solidi C, pp.1–5 / DOI 10.1002/ pssc.201400054, 2014]

Theoretical Analysis of Direct Transition in Tin Incorporated Strained QW

22000

220000

18000

16000

14000

Ö12000

Structure



• Potential of compressively strained Group IV QW structures in photonic applications is explored in this work.

- SiGe/GeSn QW structure is investigated for photo detection applications by examining its direct transition characteristics.
- The simulated results indicate that for x>0.15, GeSn well become direct band gap in nature. The peak absorption lies in short wave infrared range, so this QW structure can be used for SWIR photodetecion.

Fig: Plot of absorption coefficient for direct transition. versus wavelength for different values of *x*. HH- Γ, transition



Facilities required from IISc, Bangalore

For enhancing our research following Facilities required from IISc, Bangalore :

chemical characterization.

Proposed Facilities: RF/DC sputtering, Thermal and E-beam Evaporation system for thin film deposition under the Project: Centre of Excellence in Renewable Energy, FAST, MHRD.



- **Oxford Instruments Plasma Technology: PECVD for deposition of SiGe layer.**
- Molecular Beam Epitaxy (MBE) for deposition of GR-IV & III-V compound based layers.
- Ellipsometer to determine film thickness and optical constants of deposited layer.
- Four Point Probe Mapping System.
- Mask Aligner, MICROTECH Laser Writer, Beam Lithography system.
- First Nano's EasyTube® 6000 Horizontal Furnace System for Oxidation, Annealing, Diffusion (n-doping and p-doping) and Low Pressure Chemical Vapor Deposition (LPCVD Silicon nitride, Polysilicon (doped and undoped), SiGe and LTO).
- Film Thickness Probe for film thickness mesurement.